Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L2	1	"20050027476"	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:09
L3	1	2 and (test\$1 near site\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:17
L4	1	(linear with fit\$3 with regression\$3) and (test\$1 with site\$1) and wafer and (process\$3 near control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:18
L5	25	(linear with fit\$3 with regression\$3) and (test\$1 with site\$1) and (process\$3 near control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:20
L6	4	(("6.403,389") or ("5,627,101") or ("5.987, 398") or ("5,883.437") or ("6.466,038") or ("5,514,974") or ("6,087,189") or ("5,552, 718")).PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/15 15:20
L7	8	(("6403389") or ("5627101") or ("5987398") or ("5883437") or ("6466038") or ("5514974") or ("6087189") or ("5552718")).PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/15 15:21
L8	28	("3335340" "3974443" "4445180" "4516071" "4560583" "4722154" "4871962" "4972248" "5010029" "5561373" "5719495" "5793471" "5854097" "5857258" "5883437" "5933020" "5963784" "6019850" "6022750" "6028440" "6087189" "6291254").PN. OR ("6403389").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:32
L9	1	3 and (device\$1 near screen\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:32
L10	1	("6403389").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/15 16:21
L11	0	10 and (test\$1 and site\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:41
L12	1	10 and structure\$1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:51
L13	127	(wafer\$1 near defect\$1)with (screen\$3 monitor\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:51

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L14	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) same (fit\$3 and curve\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 15:52
L15	7	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 17:53
L16	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (test\$1site\$1)	US-PGPUB; USPAT; USOCR	OR	ON .	2007/03/15 17:54
L17	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (test with site\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 17:54
L18	0	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (ATE)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 17:54
L19	1	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (ATE tester\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 17:55
L20	1	((wafer\$1 near defect\$1)with (screen\$3 monitor\$3)) and (statistic\$3 with process\$3 with control\$3) and (ATE testers)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 17:57
L21	. 38	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 17:58
L22	0	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same (statistic\$3 with (fit\$3 GOF best\$1fit\$3))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 17:58
L23	18	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same screen\$3	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 18:00
L24	8	(wafer\$1 with tester\$1) same (process\$3 with evaluat\$3) same screen\$3 and (control\$3 with process\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 18:00
S1	681	(702/179).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/13 09:50
S2	153	(702/109,110).CCLS.	US-PGPUB; USPAT; USOCR	OR .	OFF	2007/03/13 09:50

S3	1760	(702/57,58,117).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/13 09:50
S4	426	(324/716,718).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/13 09:50
S5	0	(model\$1base\$1 near monitor\$3) and (goodness near1 fit\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 09:51
S6	4	((manipulat\$5 calculat\$5 form\$3) with (goodness near1 (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:10
S7	0	((manipulat\$5 calculat\$5 form\$3) with (goodness near1 (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)) and (independent with variable\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:10
S8	0	(((manipulat\$5 calculat\$5 form\$3) with (goodness near1 (fit\$3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)) and (independent with variable\$1)).clm.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:10
S9	681	S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:10
S10	0	S4 and S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:10
S11	0	S2 and S4	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:10
S12	2	S4 and S3	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:32
S14	0	S12 and S6	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:10
S15	0	S6 and S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:11
S16	0	S2 and S6	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:11

S17	0	S3 and S6	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:11
S18	0	S4 and S6	US-PGPUB; USPAT; USOCR	OR	ÖN	2007/03/13 10:11
S19	1	"20050027476"	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:49
S20	0	((goodness with fit\$1) with value\$1) same (independent with variable\$1) same ((measur\$4 actual) near1 value\$1) same (process\$3 near control\$1) same (form\$3 with (device\$1 structure\$1))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:51
S21	1	(monitor\$3 with (process\$3 near stability)) and (fit\$3 with value\$1) and (linear\$3 with regression\$3) and (coefficient\$1 near (relat\$3 correlat\$3))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:53
S22	. 1	(monitor\$3 with (process\$3 defect\$1 device\$1 structure\$1 wafer\$1)) and ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) and (process\$3 with control\$3 with (limit\$1 threshold\$1)) and (independent\$1 with variable\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:56
S23	0	((monitor\$3 with (process\$3 defect\$1 device\$1 structure\$1 wafer\$1)) and ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) and (process\$3 with control\$3 with (limit\$1 threshold\$1)) and (independent\$1 with variable\$1)).clm.	US-PGPUB; USPAT; USOCR	OR	ON .	2007/03/13 10:57
S24	. 0	((statisticS3 near analys\$3) and (goodness near (curve\$1 fitS4))) same (process\$3 adj control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:01
S25	0	((statisticS3 near analys\$3) and (goodness near (curve\$1 fitS4))) same (process\$3 adj control\$3) same ((calculat\$4 manipulat\$4) with (goodness near2 value\$1))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:57
S26	0	S25 and S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:57
S27	0	S25 and S2	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:57

S28	0	S25 and S3	US-PGPUB; USPAT; USOCR	OR	ÖN	2007/03/13 10:57
S29	0	S25 and S4	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:57
S30	0	((monitor\$3 with (process\$3 defect\$1 device\$1 structure\$1 wafer\$1)) same ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) same (process\$3 with control\$3 with (limit\$1 threshold\$1)) same (independent\$1 with variable\$1)).clm.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 10:58
S31	0	((monitor\$3 with (process\$3 defect\$1 device\$1 structure\$1 wafer\$1)) same ((us\$3 usag\$3) with (goodness near (curve\$1 fit\$1) near value\$1)) same (process\$3 with control\$3 with (limit\$1 threshold\$1)) same (devi\$5 with sheet with resist\$4) same (independent\$1 with variable\$1)).clm.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:00
S32	0	S31 and S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:00
S33	. 0	S31 and S2	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:00
S34	0	S31 and S3	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:00
S35	0	S31 and S4	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:00
S36	0	S31 and S6	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:01
S37	0	(((manipulat\$3 calculat\$3 formS3)with (goodness nearl (fitS3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)))and ((statisticS3 near analys\$3) and (goodness near (curve\$1 fitS4))) same (process\$3 adj control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:02

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S38	0	(((manipulat\$3 calculat\$3 form\$3)with (goodness nearl (fitS3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)))and ((statisticS3 near analys\$3) and (goodness near (curve\$1 fitS4))) same (process\$3 adj control\$3) same (monitor\$3 with (sheet\$1 with resist\$4))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:02
S39		(((manipulat\$3 calculat\$3 form\$3)with (goodness nearl (fitS3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)))and ((statistic\$3 near analys\$3) and (goodness near (curve\$1 fit\$4))near value\$1) same (process\$3 adj control\$3) same (monitor\$3 with (sheet\$1 with resist\$4))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:04
S40	0	((((manipulat\$3 calculat\$3 form\$3)with (goodness nearl (fitS3 measur\$4 statistical\$3))) and ((semiconductor\$1 wafer\$1) with (form\$3 near process\$3)))and ((statistic\$3 near analys\$3) and (goodness near (curve\$1 fit\$4))near value\$1) same (process\$3 adj control\$3) same (monitor\$3 with (sheet\$1 with resist\$4))).clm.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:06
S41	784	(700/109,110).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/13 11:06
S42	1	((curve near fit\$3) near value\$1) and (screen\$3 with (device\$1 structure\$1)) and (defect\$1 with detect\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:08
S43	23	(curve near fitt\$3) and (process\$3 with (controL\$3 monitor\$3)) and (detect\$3 with defect\$1) and (goodness near fit\$4)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:11
S44	1	S43 and S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:08
S45	0	S44 and S2	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:08
S47	0	S41 and S43	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:09

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S48	0	(curve near fitt\$3) and (process\$3 with (controL\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness nearl (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1))	US-PGPUB; USPAT; USOCR	OR	ON	
\$50	46	(curve near fitt\$3) and (process\$3 with (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness nearl (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (sheet\$1 near (resistance resistivity))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:11
S51	1	S50 and S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:11
S52	0	S50 and S41	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:11
S54	1	S50 and S43 .	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:11
S55	0	S50 and S23	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:12
S57	0	(curve near fitt\$3) and (process\$3 With (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness near1 (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (test\$3 with (structure\$1 wafer\$1)) and (model\$1 base\$1 with statistic\$3) and (form\$3 near (device\$1 structur\$3)) and ((divid\$3 divis\$3) with (parameter\$1 near sheet\$1 near resist\$4))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:17
S58		((curve near fitt\$3) and (process\$3 With (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness near1 (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (test\$3 with (structure\$1 wafer\$1)) and (model\$1 base\$1 with statistic\$3) and (form\$3 near (device\$1 structur\$3)) and ((divid\$3 divis\$3) with (parameter\$1 near sheet\$1 near resist\$4)) and (test\$1 near (condition\$1 environment\$1))).clm.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:18
S60	0	S58 and S1	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:18

`S61	0	S58 and S2	US-PGPUB; USPAT; USOCR	OR .	ON	2007/03/13 11:19
S62	335	(702/118).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/13 11:21 ,
S63	0	S6 and S62	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:21
S64	0	S62 and S58	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 11:21
S65	· 2	(("5574890") or ("6403389")).PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/03/14 11:40
S66	1	S65 and monitor\$3	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:41
S67	2	S65 and (monitor\$3 control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:41
S68	. 28	("3335340" "3974443" "4445180" "4516071" "4560583" "4722154" "4871962" "4972248" "5010029" "5561373" "5719495" "5793471" "5854097" "5857258" "5883437" "5933020" "5963784" "6019850" "6022750" "6028440" "6087189" "6291254").PN. OR ("6403389").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:46
S69	0	(process\$3 near control\$3 and monitor\$3) same (wafer\$1 semiconductor\$1) same (best near fit\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:47
S70	21	(curve near fitt\$3) and (process\$3 With (control\$3 monitor\$3)) and (detect\$3 with defect\$1) and ((goodness near1 (fit\$4 measur\$3)) (coefficient\$1 near correlation\$1)) and (test\$3 with (structure\$1 wafer\$1)) and (model\$1 base\$1 with statistic\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:47
S71	591	(process\$3 near control\$3 and monitor\$3) and (wafer\$1 semiconductor\$1) and (best near fit\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:48
S72	5	(process\$3 near control\$3 and monitor\$3) and (wafer\$1 semiconductor\$1) and (best near fit\$3) and (GOF\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:51

S73	18988	(GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) and (monitor\$3 control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:52
S74	508	(GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) with (monitor\$3 control\$3)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:52
S75	241	((GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) with (monitor\$3 control\$3)) and (measur\$4 and device\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:53
S76	19	((GOF\$1 (best\$1fit\$3) (goodness with fit\$3)) with (monitor\$3 control\$3)) same (measur\$4 and device\$1)	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:54
S77	215178	((goodness near fit\$3) (curve near fitt\$3) (fitt\$3 nearl goodness) (foodness near2 measur\$4)) same ((control\$3 near limit\$1) (threshold nearl controL\$3) (control\$3 near threshold) (limit\$3 near value\$1))	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/14 11:54